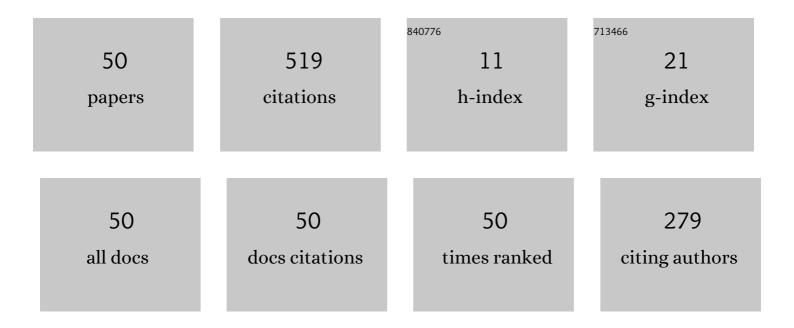
Jun-ichi Shirakashi

List of Publications by Year in descending order

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ΙΠΝ-ΙCΗΙ SΗΙΡΑΚΑSΗΙ

#	Article	IF	CITATIONS
1	Variational <i>Ansatz</i> preparation to avoid CNOT-gates on noisy quantum devices for combinatorial optimizations. AIP Advances, 2022, 12, .	1.3	6
2	Memory properties of electromigrated Au nanogaps to realize reservoir computing. Applied Physics Letters, 2021, 119, .	3.3	6
3	Machine learning-based approach for automatically tuned feedback-controlled electromigration. AIP Advances, 2020, 10, .	1.3	3
4	Gold nanogap-based artificial synapses. Japanese Journal of Applied Physics, 2020, 59, 050601.	1.5	5
5	Synaptic behaviors of electromigrated Au nanogaps. AIP Advances, 2019, 9, 055317.	1.3	4
6	Gesture Prediction Using Wearable Sensing Systems with Neural Networks for Temporal Data Analysis. Sensors, 2019, 19, 710.	3.8	17
7	Quantifying Joule Heating and Mass Transport in Metal Nanowires During Controlled Electromigration. Materials, 2019, 12, 310.	2.9	5
8	Fabrication of atomic junctions with experimental parameters optimized using ground-state searches of Ising spin computing. Scientific Reports, 2019, 9, 16211.	3.3	6
9	Simultaneous arrayed formation of single-electron transistors using electromigration in series-connected nanogaps. AIP Advances, 2018, 8, 105005.	1.3	0
10	Multiple-Junction Single-Electron Charging in Electromigrated Series-Connected Nanogaps Operating at Room Temperature. , 2018, , .		0
11	Single-Electron Tunneling Effects in Electromigrated Coulomb Island between Au Nanogaps. , 2018, , .		3
12	Fabrication of single-electron transistors with electromigrated Ni nanogaps. AIP Advances, 2018, 8, 075210.	1.3	5
13	Evolution of local temperature in Au nanowires during feedback-controlled electromigration observed by atomic force microscopy. Applied Physics Letters, 2017, 110, .	3.3	4
14	Investigation of electromigration induced by field emission current flowing through Au nanogaps in ambient air. Journal of Applied Physics, 2017, 122, .	2.5	8
15	In situ atomic force microscopy imaging of structural changes in metal nanowires during feedback-controlled electromigration. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2015, 33, 051806.	1.2	6
16	Structural tuning of nanogaps using electromigration induced by field emission current with bipolar biasing. Journal of Applied Physics, 2015, 118, .	2.5	9
17	Field-emission-induced electromigration method for precise tuning of electrical properties of Ni-based single-electron transistors. , 2015, , .		0
18	Investigation of strain sensors based on thin graphite wires. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2015, 33, .	1.2	3

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19	High-throughput nanogap formation by field-emission-induced electromigration. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2015, 33, 051801.	1.2	9
20	Simultaneous fabrication of nanogap electrodes using field-emission-induced electromigration. Journal of Applied Physics, 2015, 118, .	2.5	9
21	Ultrafast feedback-controlled electromigration using a field-programmable gate array. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2015, 33, 02B106.	1.2	11
22	Simultaneous fabrication of nanogaps using field-emission-induced electromigration. , 2014, , .		1
23	In-situ observation of temperature distribution of microheaters using near-infrared CCD imaging system. , 2013, , .		2
24	Conduction mechanism of single-electron transistors fabricated by field-emission-induced electromigration. , 2013, , .		0
25	Nanoscale mechanical scratching of graphene using scanning probe microscopy. , 2013, , .		Ο
26	Control Parameters for Fabrication of Single-Electron Transistors Using Field-Emission-Induced Electromigration. Journal of Nanoscience and Nanotechnology, 2013, 13, 993-996.	0.9	6
27	In-situ control of quantum point contacts using scanning probe microscopy scratch lithography. , 2012, , .		Ο
28	Field-emission-induced electromigration method for the integration of single-electron transistors. Applied Surface Science, 2012, 258, 2153-2156.	6.1	19
29	Fabrication of planar-type Ni/vacuum/Ni tunnel junctions based on ferromagnetic nanogaps using field-emission-induced electromigration. Journal of Applied Physics, 2011, 109, 07C919.	2.5	5
30	Tuning of Tunnel Resistance of Nanogaps by Field-Emission-Induced Electromigration Using Current Source Mode. Journal of Nanoscience and Nanotechnology, 2011, 11, 6266-6270.	0.9	5
31	Integration of Single-Electron Transistors Using Field-Emission-Induced Electromigration. Journal of Nanoscience and Nanotechnology, 2011, 11, 6258-6261.	0.9	11
32	Simultaneous tuning of tunnel resistance of integrated nanogaps by field-emission-induced electromigration. , 2011, , .		0
33	SINGLE-ELECTRON TRANSISTORS FABRICATED BY FIELD-EMISSION-INDUCED ELECTROMIGRATION. , 2011, , .		0
34	Fabrication of Single-Electron Transistors Using Field-Emission-Induced Electromigration. Journal of Nanoscience and Nanotechnology, 2010, 10, 7239-7243.	0.9	22
35	Fabrication of planar-type ferromagnetic tunnel junctions using electromigration method and its magnetoresistance properties. Journal of Physics: Conference Series, 2010, 200, 062035.	0.4	3
36	Influence of Feedback Parameters on Resistance Control of Metal Nanowires by Stepwise Feedback-Controlled Electromigration. Journal of Nanoscience and Nanotechnology, 2010, 10, 7464-7468.	0.9	11

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37	Scanning Probe Microscope Lithography at the Micro- and Nano-Scales. Journal of Nanoscience and Nanotechnology, 2010, 10, 4486-4494.	0.9	12
38	Fabrication of nanogap electrodes by field-emission-induced electromigration. Journal of Vacuum Science & Technology B, 2009, 27, 813-816.	1.3	28
39	Scratching properties of nickel-iron thin film and silicon using atomic force microscopy. Journal of Applied Physics, 2009, 106, 044314.	2.5	43
40	AFM Nanoâ€oxidation of NiFe Thin Films Capped with Alâ€Oxide Layers for Planarâ€type Tunnel Junction. IEEJ Transactions on Electrical and Electronic Engineering, 2008, 3, 382-385.	1.4	1
41	Magnetization Switching of Magnetic Submicron Structure Fabricated by Atomic Force Microscope. IEEJ Transactions on Electrical and Electronic Engineering, 2008, 3, 386-389.	1.4	Ο
42	Wide-range control of tunnel resistance on metallic nanogaps using migration. Journal of Physics: Conference Series, 2008, 100, 052022.	0.4	19
43	Control of Tunnel Resistance of Nanogaps by Field-Emission-Induced Electromigration. Japanese Journal of Applied Physics, 2007, 46, L907-L909.	1.5	35
44	Planar-type ferromagnetic tunnel junctions fabricated by SPM local oxidation. Journal of Magnetism and Magnetic Materials, 2007, 310, e641-e643.	2.3	7
45	Magnetoresistance effect of planar-type ferromagnetic tunnel junctions. Journal of Applied Physics, 2006, 99, 08T312.	2.5	10
46	Magnetoresistance of patterned NiFe thin films with structures modified by atomic force microscope nanolithography. Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena, 2005, 23, 2390.	1.6	5
47	Tunnel magnetoresistance on ferromagnetic single-electron transistors with multiple tunnel junction. Journal of Applied Physics, 2001, 89, 7365-7367.	2.5	13
48	Room Temperature Nb-Based Single-Electron Transistors. Japanese Journal of Applied Physics, 1998, 37, 1594-1598.	1.5	28
49	Single-electron charging effects in Nb/Nb oxide-based single-electron transistors at room temperature. Applied Physics Letters, 1998, 72, 1893-1895.	3.3	100
50	298 K operation of Nb/Nb oxide-based single-electron transistors with reduced size of tunnel junctions by thermal oxidation. Journal of Applied Physics, 1998, 83, 5567-5569.	2.5	14